

EAST Search History

JWS

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L2	98	((batch or plural or multiplr) near8 (wafer or semiconductor or substrate or workpiece) near8 (rotor or chuck or spindle or spinning or spin or spun or rotat\$3 or rotary)) and (steam\$4 or ((water) near12 (boil\$4 or vapor\$5 or gaseous or mist or fog or atomi\$5)))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/17 05:54
L17	40	(((((batch or plural or multiple or boat) near8 (wafer or semiconductor or substrate or workpiece)) and (rotor or chuck or spindle or spinning or spin or spun or rotat\$3 or rotary))) and ((organic near1 solvent) or ipa or alcohol) and (ozon\$4 near8 (spag\$4 or bubbl\$4)))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/17 06:46
S14	444	((wafer or semiconductor or substrate or workpiece) near5 (rotor or chuck or spindle or spinning or spin or spun or rotat\$3 or rotary)) and ((water or steam\$4) near12 (boil\$4 or vapor\$5 or gaseous or mist or fog or atomi\$5)) and (ozone near5 (vapor or gas or gaseous or fog or atomiz\$5 or aerosol or atmosphere))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/17 05:13
S18	102	((wafer or semiconductor or substrate or workpiece) near5 (rotor or chuck or spindle or spinning or spin or spun or rotat\$3 or rotary)) and (steam\$4 or ((water) near12 (boil\$4 or vapor\$5 or gaseous or mist or fog or atomi\$5))) and (ozone near5 (vapor or gas or gaseous or fog or atomiz\$5 or aerosol or atmosphere)) and ((wafer or semiconductor or substrate or workpiece) near8 (risn\$4 or flush\$4 or "pure water"))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/17 05:51
S24	168	((wafer or semiconductor or substrate or workpiece) near5 (rotor or chuck or spindle or spinning or spin or spun or rotat\$3 or rotary)) and (steam\$4 or (water near12 (boil\$4 or vapor\$5 or gaseous or mist or fog or atomi\$5) near12 (heater))) and (ozone near5 (vapor or gas or gaseous or fog or atomiz\$5 or aerosol or atmosphere))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/17 05:21

EAST Search History

JWS

S30	200	((wafer or semiconductor or substrate or workpiece) near5 (rotor or chuck or spindle or spinning or spin or spun or rotat\$3 or rotary)) and (steam\$4 or (water near12 (boil\$4 or vapor\$5 or gaseous or mist or fog or atomi\$5) near12 (heater))) and (single near5 (tank or reactor or tank or vessel or chamber))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/04/17 05:27
-----	-----	--	---	----	----	------------------